

## SYSTEM AND METHOD FOR MONITORING CONTAMINATION

## ABSTRACT OF THE DISCLOSURE

The present invention provides passive sampling systems and methods for monitoring contaminants in a semiconductor processing system. In one embodiment,  
5 that passive sampling system comprises a collection device in fluid communication with a sample line that provides a flow of gas from a semiconductor processing system. The collection device is configured to sample by diffusion one or more contaminants in the flow of gas.